



1753

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Chung-En Kao

Group Art Unit: 1753

Serial No.: 09/976,082

Examiner: Steven H. Versteeg

#3/A
W.M.
2/27/03

Filed: Oct. 12, 2001

In Response to Office Action
Dated: November 8, 2002

For: Apparatus And Method For Self-Centering A Wafer
In A Sputter Chamber

Attorney Docket No.: 67,200-530

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Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231.

Kathy Dixon

Date: Feb 12, 2003

RESPONSE TO OFFICE ACTION

Assistant Commissioner
for Patents
Washington, D.C. 20231

Dear Sir:

In response to an Office Action mailed Nov. 8, 2002, please enter the following amendments and consider the following remarks. Applicants hereby respectfully request and petition for

03/24/2003 WHITEH 06000002 500484 09976082
01 FC:1251 110.00 CH
extension of time up to and including March 8, 2003 to
respond to the Official Action dated November 8, 2002